

200mm Semi-Automatic Probe Station

The WaveLink 250 represents the upper limit in computer-controlled analytical wafer probing. Designed to be the flagship of our RF/MW line, it is equally at home at 5 fA as it is at 110 GHz. Whether you simply need EMI or RFI isolation, or frost-free characterization at -65 °C, the WL-250 should be your platform of choice. SIGNATONE, you asked - *We Listened!*



PERFORMANCE, QUALITY, VALUE

SIGNATONE®

Advanced Microprobing Solutions Since 1968

Specifications

- ◆ 200mm XY stage travel
- ◆ Independent cal and wafer chuck
- ◆ 50mm platen range, with lock
- ◆ 50mm programmable microscope transport
- ◆ Pneumatic 4" microscope lift
- ◆ Chuck X-Y Resolution: .1 μ
- ◆ Chuck X-Y Repeatability: 1 μ
- ◆ Chuck X-Y Accuracy: $\pm 3\mu$
- ◆ Chuck Z Resolution: .1 μ
- ◆ Chuck Z Accuracy: .25 μ
- ◆ Chuck Θ : ± 6 degrees

X-Y Motion Control

- ◆ "Point & Shoot" movements
- ◆ 8 directional arrows with variable speed control
- ◆ Wafer map "Pick & Move"
- ◆ "Go To" commands

Z Motion Control

- ◆ Separate contact/overdrive height
- ◆ Z motion speed control
- ◆ Safety lock
- ◆ Soft Z with edge sense circuit (for use w/probe card edge sense)

User-Friendly Features

- ◆ Stores setup and programs for easy retrieval
- ◆ Icons for most applications
- ◆ Basic Run mode guides the user through basic operations
- ◆ On-Screen video display option
- ◆ Wafer map position indicator

Integrated Probing Solutions For Testing

- ◆ S-Parameters, 1/f
- ◆ Load-Pull, Noise Figure
- ◆ V_{TH}
- ◆ T_{OX}
- ◆ CV/IV
- ◆ Sub-Threshold Leakage to 5 fA
- ◆ Resistivity
- ◆ WLR
- ◆ Dark Current
- ◆ Pulse mode 10A/100V Measurements

Programming

- ◆ Wafer Map design editor
- ◆ Selective programming
- ◆ Learn position
- ◆ Subroutine with chuck or Computer aided Probe

Interfacing

- ◆ DDE interface integrated with ICS Metrics for instrument control of most Keithley and Agilent instruments
- ◆ Application SW for Keithley 2400 Series
- ◆ DDE compatible with HP VEE
- ◆ DDE compatible with NI LABView
- ◆ GPIB compatible with NI LABView

Other Features

- ◆ Microscope X-Y-Z and Zoom control
- ◆ Color wafer bin mapping with 16 colors
- ◆ Hot chuck interface and control
- ◆ Accepts probe cards
- ◆ Available vibration isolation tables
- ◆ Optional Controller/Instrumentation rack

ICS-Metrics Software

- ◆ ICS-Metrics integrates Agilent and Keithley DC/CV instrumentation for the automated characterization of semiconductor parameters
- ◆ Graphical user interface for all instrument functions
- ◆ Simple, pre-configured test formats for semiconductor devices
- ◆ Data collection and storage
- ◆ Sequential test execution
- ◆ Data analysis and reporting